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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: Sreenivasan et al.
App. No.: 10/670,980 GPAU: 1722
Filing Date: 09/25/2003 Examiner: Nguyen, Thukhanh
Dkt. No.: P100-42-03 Conf. No.: 8096
For: IMPRINT LITHOGRAPHY TEMPLATE HAVING OPAQUE ALIGNMENT MARKS

INFORMATION DISCLOSURE STATEMENT

Mail Stop AMENDMENT
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

The following information is submitted in compliance with Applicants' duty of disclosure and pursuant to 37 C.F.R. § 1.56, § 1.97 and § 1.98. The undersigned brings the patents, publications, applications or other information identified in the attached:

- ☒ Form(s) PTO/SB/08A and/or PTO/SB/08B or PTO/1449
☐ Other:

to the Examiner's attention in the above-identified application. It is respectfully requested that the cited information be expressly considered during the prosecution of this application, and the references be made of record therein and appear among the "references cited" on any patent to issue therefrom.

This Information Disclosure Statement is being filed:

before the mailing date of a first Office action on the merits or before the mailing date of a first Office action after the filing of a request for continued examination under § 1.114. Therefore, no fee is believed required.

Applicant(s) does not believe that any additional fees are due, but if the Commissioner believes additional fees are due,

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Date: 1-14-05

Respectfully Submitted,



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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

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Sheet

1

of

23

Complete if Known

Application Number	10/670,980
Filing Date	09/25/2003
First Named Inventor	Sreenivasan et al.
Group Art Unit	1722
Examiner Name	Nguyen, Thukhanh
Attorney Docket Number	P100-42-03

U.S. PATENT DOCUMENTS

Examiner Initials*	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
	B1	3,527,062		Belinski et al.	09-08-1970	
	B2	3,783,520		King	01-08-1974	
	B3	3,807,027		Heisler	04-30-1974	
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	B5	3,811,665		Seelig	05-21-1974	
	B6	4,062,600		Wyse	12-13-1977	
	B7	4,070,116		Frosch et al.	01-24-1978	
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	B9	4,119,688		Hiraoka	10-10-1978	
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	B18	4,426,247		Toshiakai et al.	01-17-1984	
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	B20	4,451,507		Beltz et al.	05-29-1984	
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	B22	4,544,572		Sandvig et al.	10-01-1985	
	B23	4,552,832		Blume et al.	11-12-1985	
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	B31	4,724,222		Feldman	02-09-1988	
	B32	4,731,155		Napoli et al.	03-15-1988	
	B33	4,737,425		Lin et al.	04-12-1988	
	B34	4,763,886		Takei	08-16-1988	
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				Group Art Unit	1722
				Examiner Name	Nguyen, Thukhanh
				Attorney Docket Number	P100-42-03
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	B35	4,772,878		Kane	09-20-1988	
	B36	4,808,511		Holmes.	02-28-1989	
	B37	4,826,943		Ito et al.	05-02-1989	
	B38	4,846,931		Gmitter et al.	07-11-1989	
	B39	4,848,179		Ubhayakar	07-18-1989	
	B40	4,848,911		Uchida et al.	07-18-1989	
	B41	4,857,477		Kanamori	08-15-1989	
	B42	4,883,561		Gmitter et al.	11-28-1989	
	B43	4,887,283		Hosno	12-12-1989	
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	B45	4,908,298		Hefferon et al.	03-13-1990	
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	B51	4,959,252		Bonnebat et al.	09-25-1990	
	B52	4,964,145		Maldonado	10-16-1990	
	B53	4,964,945		Calhoun et al.	10-23-1990	
	B54	4,976,818		Hashimoto et al.	12-11-1990	
	B55	4,980,316		Huebner	12-25-1990	
	B56	4,999,280		Hiraoka	03-12-1991	
	B57	5,053,318		Gulla et al.	10-01-1991	
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	B59	5,071,694		Uekita et al.	12-10-1991	
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	B64	5,110,514		Soane	05-05-1992	
	B65	5,126,006		Cronin et al.	06-30-1992	
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	B68	5,151,754		Ishibashi et al.	09-29-1992	
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		Group Art Unit	1722		
		Examiner Name	Nguyen, Thukhanh		
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	B69	5,155,749		DiMilia et al.	10-13-1992	
	B70	5,169,494		Hashimoto et al.	12-08-1992	
	B71	5,171,490		Fudim	12-15-1992	
	B72	5,173,393		Sezi et al.	12-22-1992	
	B73	5,179,863		Uchida et al.	01-19-1993	
	B74	5,198,326		Hashimoto et al.	03-30-1993	
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	B76	5,206,983		Guckel et al.	05-04-1993	
	B77	5,212,147		Sheats	05-18-1993	
	B78	5,218,193		Miyatake	06-08-1993	
	B79	5,234,793		Sebald et al.	08-10-1993	
	B80	5,240,550		Boehnke et al.	08-31-1993	
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	B82	5,242,711		DeNatale et al.	09-07-1993	
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	B86	5,277,749		Griffith et al.	01-11-1994	
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	B88	5,318,870		Hartney	06-07-1994	
	B89	5,324,683		Fitch et al.	06-28-1994	
	B90	5,328,810		Lowrey et al.	07-12-1994	
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	B93	5,355,219		Araki et al.	10-11-1994	
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	B102	5,417,802		Obeng	05-23-1995	
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Application Number		10/670,980			
Filing Date		09/25/2003			
First Named Inventor		Sreenivasan et al.			
Group Art Unit		1722			
Examiner Name		Nguyen, Thukhanh			
Attorney Docket Number		P100-42-03			
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		Number	Kind Code ² (if known)			
	B103	5,421,981		Leader et al.	06-06-1995	
	B104	5,422,295		CHOI et al.	06-06-1995	
	B105	5,424,549		Feldman	06-13-1995	
	B106	5,425,848		Haisma et al.	06-20-1995	
	B107	5,425,964		Southwell et al.	06-20-1995	
	B108	5,431,777		Austin	07-11-1995	
	B109	5,439,766		Day et al.	08-08-1995	
	B110	5,452,090		Progler et al.	09-19-1995	
	B111	5,453,157		Jeng	09-26-1995	
	B112	5,458,520		DeMercurio et al.	10-17-1995	
	B113	5,468,542		Crouch	11-21-1995	
	B114	5,480,047		Tanigawa et al.	01-02-1996	
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	B118	5,512,131		Kumar et al.	04-30-1996	
	B119	5,515,167		Ledger et al.	05-07-1996	
	B120	5,523,878		Wallace et al.	06-04-1996	
	B121	5,527,662		Hashimoto et al.	06-18-1996	
	B122	5,545,367		Bae et al.	08-13-1996	
	B123	5,563,702		Emery et al.	10-08-1996	
	B124	5,566,584		Briganti	10-22-1996	
	B125	5,633,505		Chung et al.	05-27-1997	
	B126	5,654,238		Cronin et al.	08-05-1997	
	B127	5,669,303		Maracas et al.	09-23-1997	
	B128	5,670,415		Rust	09-23-1997	
	B129	5,700,626		Lee et al.	12-23-1997	
	B130	5,723,176		Keyworth et al.	03-03-1998	
	B131	5,724,145		Kondo et al.	03-03-1998	
	B132	5,725,788		Maracas et al.	03-10-1998	
	B133	5,726,548		Chiba et al.	03-10-1998	
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	B135	5,736,424		Prybyla et al.	04-07-1998	
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	B137	5,747,102		Smith et al.	05-05-1998	
	B138	5,753,014		Van Rijn	05-19-1998	
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	B149	5,876,550		Feygin et al.	03-02-1999	
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	B151	5,877,861		Ausschnitt et al.	03-02-1999	
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	B153	5,888,650		Calhoun et al.	03-30-1999	
	B154	5,895,263		Carter et al.	04-20-1999	
	B155	5,900,160		Whitesides et al.	05-04-1999	
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	B157	5,912,049		Shirley	06-15-1999	
	B158	5,926,690		Toprac et al.	07-20-1999	
	B159	5,937,758		Maracas et al.	08-17-1999	
	B160	5,942,871		Lee	08-24-1999	
	B161	5,948,219		Rohner	09-07-1999	
	B162	5,948,470		Harrison et al.	09-07-1999	
	B163	5,948,570		Kornblut et al.	09-07-1999	
	B164	5,952,127		Yamanaka	09-14-1999	
	B165	5,988,859		Kirk	11-23-1999	
	B166	6,033,977		Gutsche et al.	03-07-2000	
	B167	6,035,805		Rust	03-14-2000	
	B168	6,036,055		Mogadam et al.	03-14-2000	
	B169	6,038,280		Rossiger et al.	03-14-2000	
	B170	6,039,897		Lochhead et al.	03-21-2000	
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		Number	Kind Code ² (if known)			
	B171	6,046,056		Parce et al.	04-04-2000	
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	B174	6,081,334		Brimbergen et al.	06-27-2000	
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	B179	6,125,183		Jiawook et al.	09-26-2000	
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	B181	6,133,576		Shafer et al.	10-17-2000	
	B182	6,137,562		Masuyuki et al.	10-24-2000	
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	B189	6,188,150	B1	Spence	02-13-2001	
	B190	6,204,922	B1	Chalmers	03-20-2001	
	B191	6,218,316	B1	Marsh	04-17-2001	
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	B193	6,245,213	B1	Olsson et al.	06-12-2001	
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	B196	6,309,580	B1	Chou	10-30-2001	
	B197	6,316,290	B1	Wensel	11-13-2001	
	B198	6,326,627	B1	Putvinski et al.	12-04-2001	
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	B204	6,383,928	B1	Eissa	05-07-2002	
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				First Named Inventor	Sreenivasan et al.
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				Examiner Name	Nguyen, Thukhanh
				Attorney Docket Number	P100-42-03
Sheet	7	of	23		

U.S. PATENT DOCUMENTS						
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		Number	Kind Code ² (if known)			
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	B206	6,387,787	B1	Mancini et al.	05-14-2002	
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				Examiner Name	Nguyen, Thukhanh
Sheet	8	of	23	Attorney Docket Number	P100-42-03

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		Number	Kind Code ² (if known)			
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	B240	6,677,252	B2	Marsh	01-13-2004	
	B241	6,696,157	B1	David et al.	02-24-2004	
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Application Number		10/670,980			
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First Named Inventor		Sreenivasan et al.			
Group Art Unit		1722			
Examiner Name		Nguyen, Thukhanh			
Attorney Docket Number		P100-42-03			
Sheet	9	of	23		

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		Number	Kind Code ² (if known)			
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	B305	2004/0168586	A1	Bailey et al.	09-02-2004	
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	B321	DE	2800476		Lamprecht et al.	07-13-1978		
	B322	EP	0867775		Shinji	09-30-1998		
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	B347	WO	02/006902		Choil et al.	01-24-2002		
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	B351	WO	02/22916		Pettersson et al.	03-21-2002		
	B352	WO	02/24977		Bjarnason et al.	03-28-2002		
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	B354	WO	92/17883		Olsson	10-15-1992		

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				Group Art Unit	1722
				Examiner Name	Nguyen, Thukhanh
Sheet	13	of	23	Attorney Docket Number	P100-42-03

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	B358	Abstract of Japanese Patent 02-24848, January 26, 1990	
	B359	Abstract of Japanese Patent 02-92603, August 12, 2004	
	B360	Abstract of Japanese Patent 55-88332, April 14, 2004	
	B361	Abstract of Japanese Patent 57-7931, April 14, 2004	
	B362	Abstract of Japanese Patent 58-129074, August 01, 1983	
	B363	Abstract of Japanese Patent 63-138730, April 14, 2004	
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	B367	"Photoresist Coating Methods.", E-mail from Susan Bagen (BAGEN@aol.com) to Dhaval Shah, September 18, 1997.	
	B368	BENDER et al., "Fabrication of Nanostructures using a UV-based Imprint Technique.", Microelectronic Engineering 53, January 1, 2000, pp. 233-236.	

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	B369	BENDER et al., "Multiple Imprinting in UV-based Nanoimprint Lithography: Related Material Issues.", Microelectronic Engineering 61 – 62, January 1, 2002, pp. 407-413.	
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	B394	HEXEL CORPORATION, "Tornado 2000 System Specifications.", www.hexel.com , November 12, 1999.	
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	B396	HIRAI et al., "Mold Surface Treatment for Imprint Lithography.", Journal of Photopolymer Science and Technology, August 1, 2001, Vol. 14, No. 3, pp. 457-462.	
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	B398	HOLLIS et al., "A Six-Degree-of-Freedom Magnetically Levitated Variable Compliance Fine-Motion Wrist: Design, Modeling, and Control.", IEEE Transactions on Robotics and Automation, June 1, 1991, Vol 7., No. 3, pp. 320 - 332.	
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	B402	International Search Report for PCT/US 01/26049, February 19, 2002	
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	B409	KRAUSS et al., "Fabrication of Nanodevices Using Sub-25 nm Imprint Lithography.", Appl. Phy. Lett., January 1, 1995, 67 (21), pp. 3114-3116.	
	B410	KRUG et al., "Fine Patterning of Thin Sol-gel Films.", Journal of Non-Crystalline Solids, January 1, 1992, 147 & 148, pp. 447-450.	
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	B412	LEE et al., "An Ultraprecision Stage for Alignment of Wafers in Advanced Microlithography.", Precision Engineering, September 1, 1997, pp. 113-122.	

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	B413	LEE et al., "Ultra Precision Positioning System for Servo Motor-piezo Actuator Using the Dual Servo Loop and Digital filter Implementation.", American Society for Precision Engineering, January 1, 1998, pp. 287-290.	
	B414	LIN, "Multi-Layer Resist Systems.", Introduction to Microlithography, February 14, 1983, pp. 287-349.	
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	B423	NERAC.COM Retro Search, "Imprint Lithography." October 16, 2004.	

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	B435	PHYSIK INSTRUMENTS, "Hexapod Six-Axis Parallel Kinematics Robot", Nano Positioning, January 1, 1998, pp. 8.4 – 8.5.	
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Sheet	21	of	23	Attorney Docket Number	P100-42-03

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	B446	SLOCUM, "Precision Machine Design: Macromachine Design Philosophy and Its Applicability to the Design of Micromachines.", Micro Electro Mechanical Systems, February 4, 1992.	
	B447	SOWAH, "Diamond Used to Break the Mould [online].", [Retrieved on Sept. 2, 2003.] Retried from the Internet: <URL: http://eetuk.com/showArticle.jhtml?articleID=19203691 >., 9/18/02.	
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	B449	STEWART, "A Platform With Six Degrees of Freedom.", Proc Instn Mech Engrs, May 28, 1965, Vol 180, Pt1, No. 15, pp. 371-378.	
	B450	STIX, "Getting More from Moores", Scientific American, 4/2001.	
	B451	TAJBAKSH et al., "Three-Degree-of-Freedom Optic Mount for Extreme Ultraviolet.", American Society for Precision Engineering, January 1, 1998, pp. 359-362.	
	B452	TANIKAWA et al., "Development of Small-sized 3 DOF Finger Module in Micro Hand for Micro Manipulation.", Proc. of IEEE, March 1, 1999, Intl. conf. on Intelligent Robots and Systems, pp. 876-881.	
	B453	TOMITA et al., "A 6-axes Motion Control Method for Parallel-Linkage-Type Fine Motion Stage.", JSPE-58-04, pp. 118-124., 11/11/2002	
	B454	Translation of Japanese Patent 02-24848, January 26, 1990.	
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	B456	TRILOGY SYSTEMS, "Linear Motors 310.", www.trilogysystems.com , January 1, 2001.	

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				Application Number	10/670,980
				Filing Date	09/25/2003
				First Named Inventor	Sreenivasan et al.
				Group Art Unit	1722
				Examiner Name	Nguyen, Thukhanh
Sheet	22	of	23	Attorney Docket Number	P100-42-03

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	B457	UCHIDA et al., "A Mask-to-Wafer Alignment and Gap Setting Method for X-ray Lithography Using Graftings.", Journal Vacuum Science Technology, November 1, 1991, B 9 (6), pp. 3202-3206.	
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	B459	US Application No. 10/463,396, Filed 06-17-2003, CHOI et al., "Method to Reduce Adhesion Between a Conformable Region and a Pattern of a Mold."	
	B460	US Application No. 10/614,716, Filed 07-07-2003, SREENIVASAN et al., "A Conforming Template for Patterning Liquids Disposed on Substrates."	
	B461	US Application No. 10/687,519, Filed 10-16-2003, TRUSKETT et al., "Low Surface Energy Templates."	
	B462	US Application No. 10/687,562, Filed 10-16-03, CHERALA et al., "Applying Imprinting Material to Substrates Employing Electromagnetic Fields."	
	B463	US Application No. 10/760,821, Filed 01-20-2004, SREENIVASAN et al., "Method for Concurrently Employing Differing Materials to Form a Substrate."	
	B464	US Application No. 10/785,248, Filed 02-24-2004, CHOI et al., "A Method to Control the Relative Position Between a Body and a Surface."	
	B465	US Application No. 10/788,700, Filed 02-27-2004, SREENIVASAN et al., "Full-Wafer or Large Area Imprinting with Multiple Separated Sub-Fields for High Throughput Lithography."	
	B466	US Application No. 10/864,214, Filed 6-9-04, SREENIVASAN et al., "An Imprint Lithography System to Produce a Light to Impinge upon and Polymerize a Liquid in Superimposition with Template Overlay Marks."	
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	B468	US Applications No. 10/616,294, Filed 07-09-2003, CHOI et al., "Systems for Magnification and Distortion Correction for Imprint Lithography Processes."	
	B469	VANDERBILT, "VU9730 Specifications for Improved Flexure Device.", Vanderbilt University Office of Transfer Technology, 101, 25, 192-199, 01/01/2003.	
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	B471	WHITE et al., "Novel Alignment System for Imprint Lithography.", J. Vac. Sci. Technol. B 18(6), November 1, 2000, pp. 3552-3556.	
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	B473	WU, "Large Area High Density Quantized Magnetic Disks Fabricated Using Nanoimprint Lithography.", J. Vac. Sci. Technol., November 1, 1998, B 16(6), pp. 3825-3829.	
	B474	XIA et al., "Soft Lithography.", Angew. Chem. Int. Ed., January 1, 1998, pp. 551-575.	
	B475	XIA et al., "Soft Lithography.", Annu Rev. Mater. Sci., 1998, 28: 153-184.	

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